

219 Thin MoS₂ layer grown on SiO₂ by CVD method

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The Transition metal dichalcogenides (TMD), MX₂ (M=Mo, W; X=S, Se, Te), inorganic graphene analogues, have attracted substantial attention due their great potential in various fields as catalysis, nanotribology, microelectronics, lithium batteries, hydrogen storage, medical and optoelectronics [1]. Especially MoS₂ due to the direct gap, that presents the monolayer, promises applications in optoelectronics.

Substantial efforts have been addressed to growing of thin-layer MoS₂, using various methods including scotch tape based micromechanical exfoliation and, chemical exfoliation of bulk material, chemical vapor deposition (CVD), among other techniques [2].

In this work, CVD method was used to explore the growing of thin MoS₂ layer. MoS₂ (mono and few layer) was grown directly on SiO₂/Si substrates using MoO₃ powder. By optical microscopy was possible to identify MoS₂ layer-regions based on the optical contrast. Raman spectroscopy (laser $\lambda=532$ nm) analysis showed two typical active modes: E_{2g}¹ and A_{1g} [3]. These modes of vibration have been investigated both theoretically and empirically in MoS₂ bulk. E_{2g}¹ mode indicates planar vibration and A_{1g} mode is associated with the vibration of sulfides in the out-of-plane direction. Raman peak position of ν E_{2g}¹ and A_{1g} was used in order identify the thickness of the layers [3]. The peaks were found to be blue-shift for E_{2g}¹ and red-shift for A_{1g} when it compared mono layer with MoS₂ bulk.

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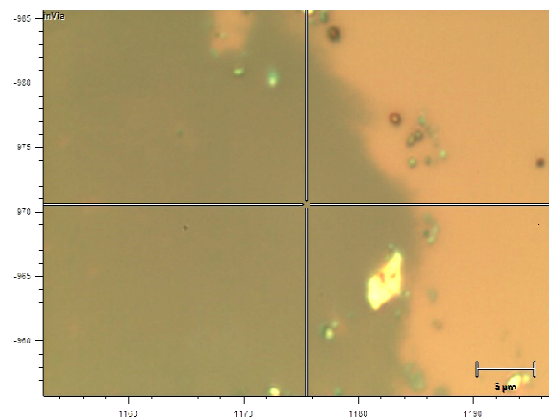


Figure 1. Optical image of thin MoS₂ film onto SiO₂/Si substrate.

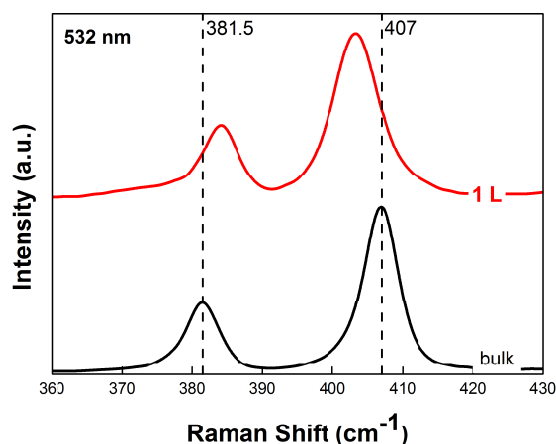


Figure 2. Raman spectrum for bulk and mono-layer MoS₂ (laser $\lambda=532$ nm).

References

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